

1/11

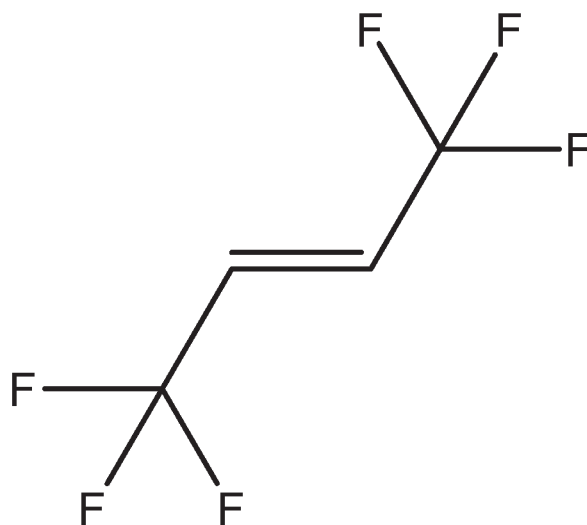


FIG 1

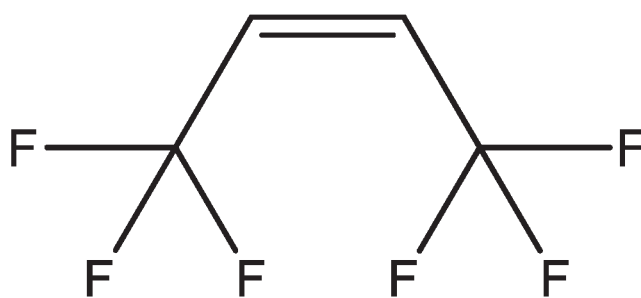


FIG 2

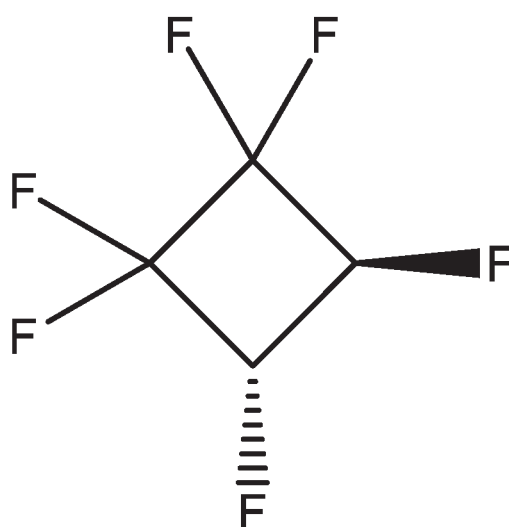


FIG 3

2/11

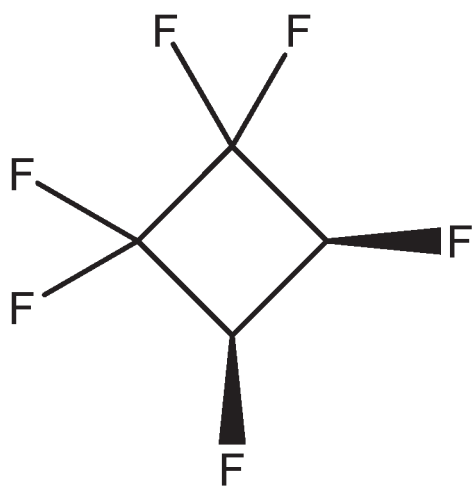


FIG 4

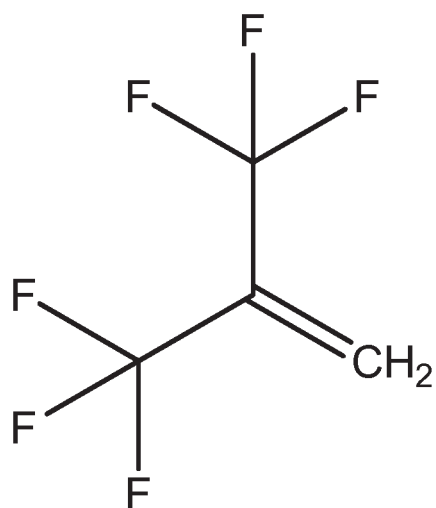


FIG 5

3/11

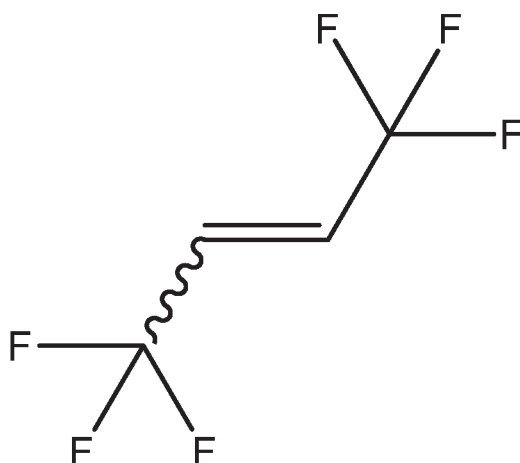


FIG 6

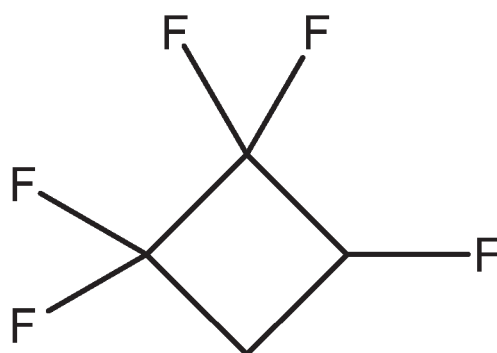


FIG 7

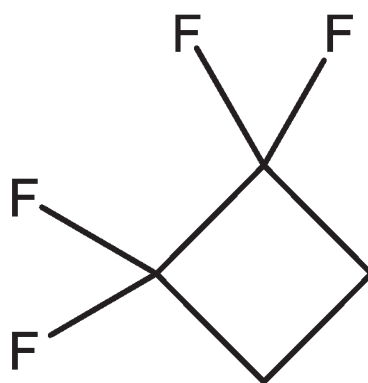


FIG 8

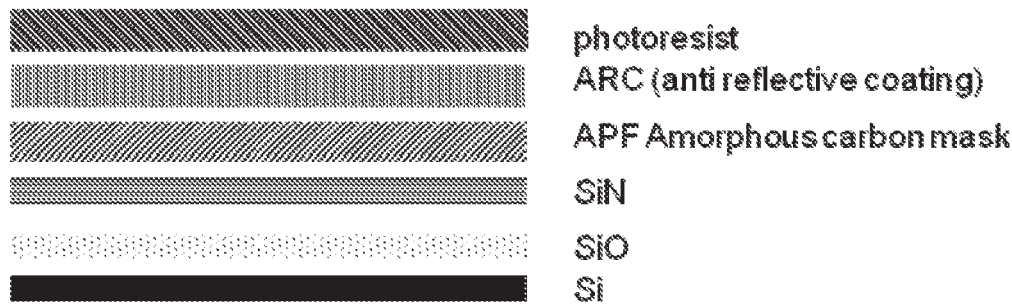
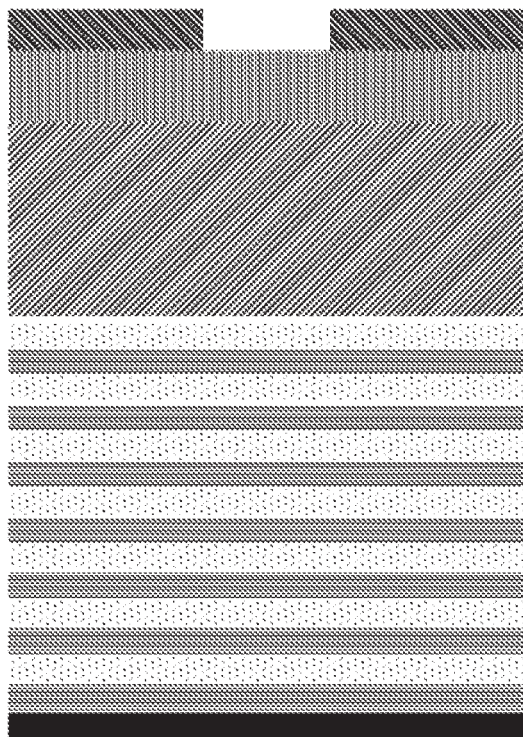


FIG 9

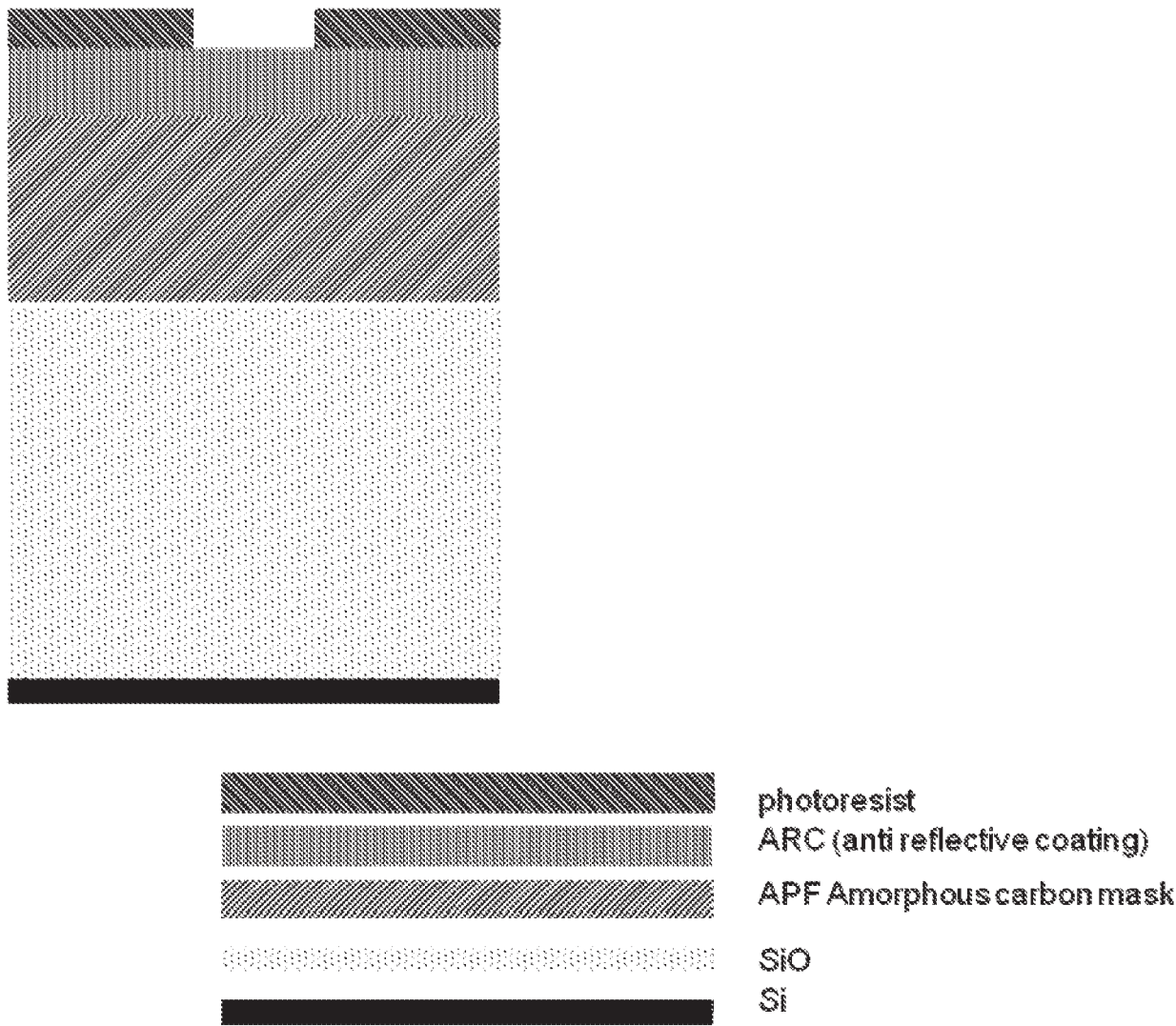


FIG 10

6/11

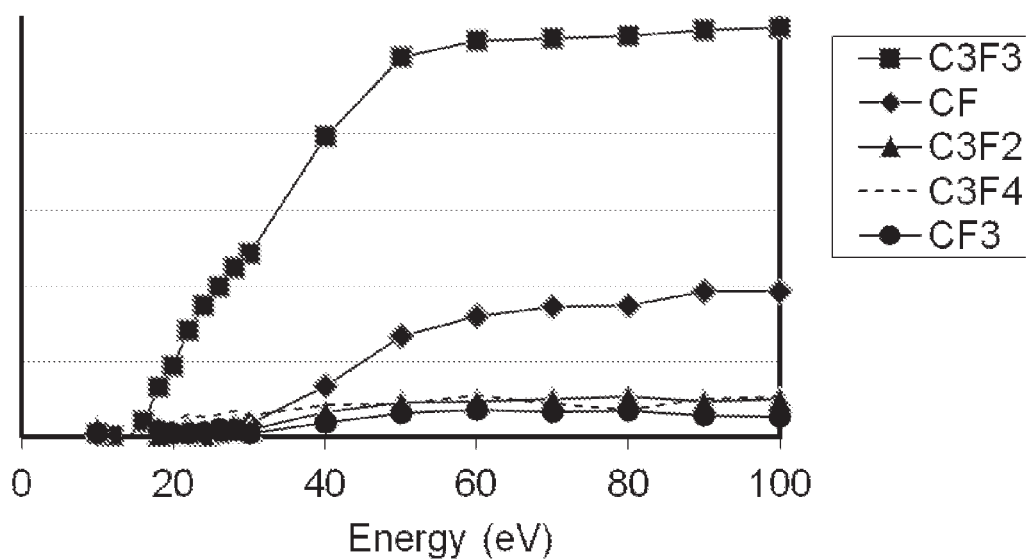
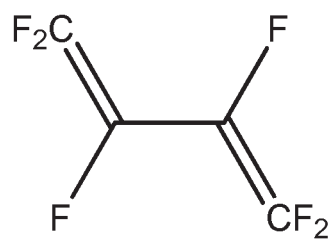


FIG 11

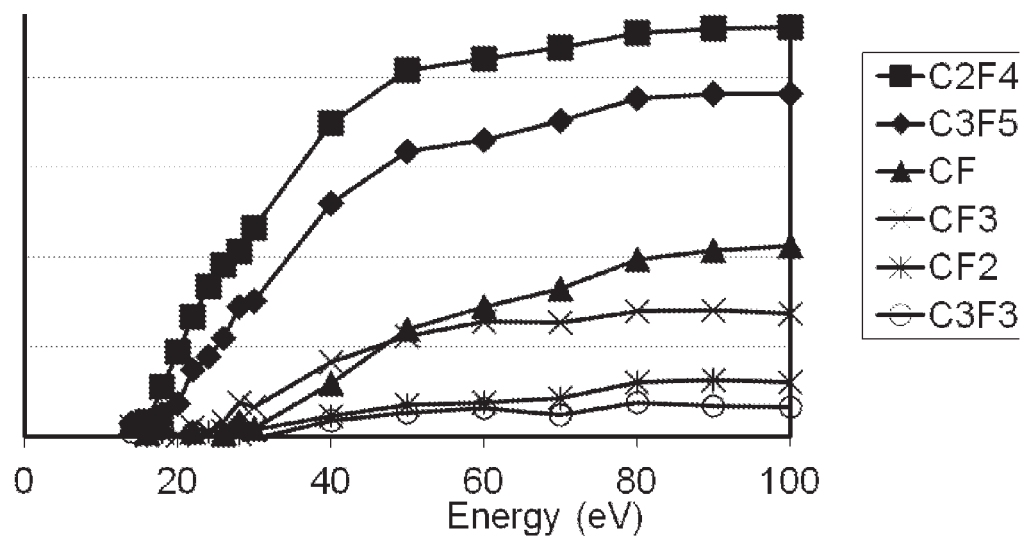
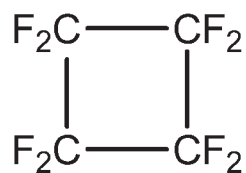


FIG 12

7/11

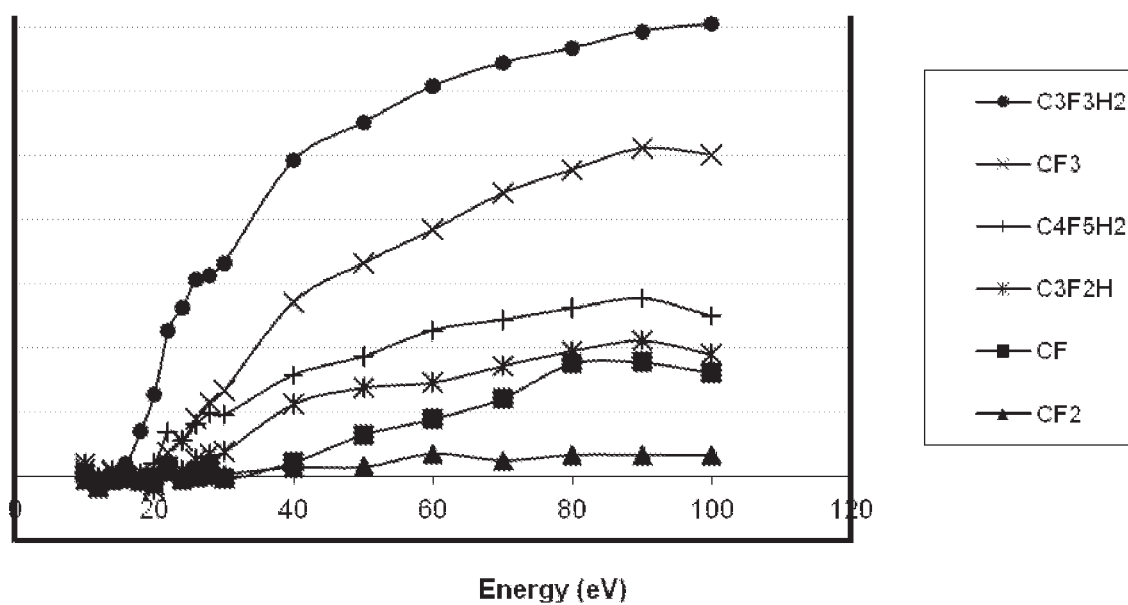


FIG 13

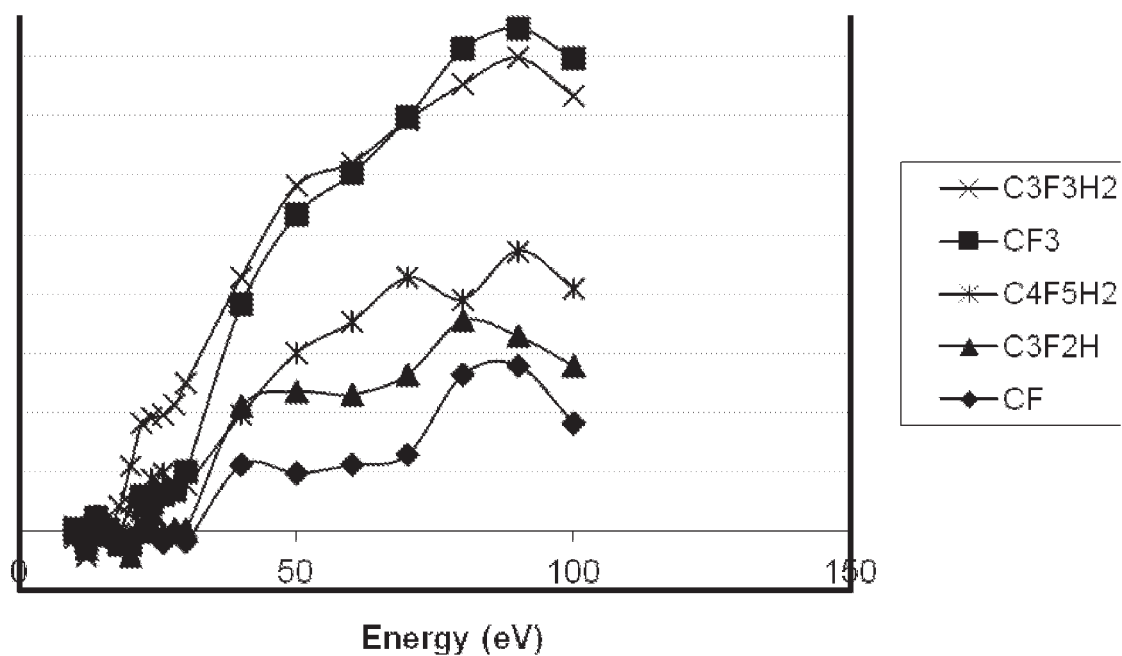


FIG 14

8/11

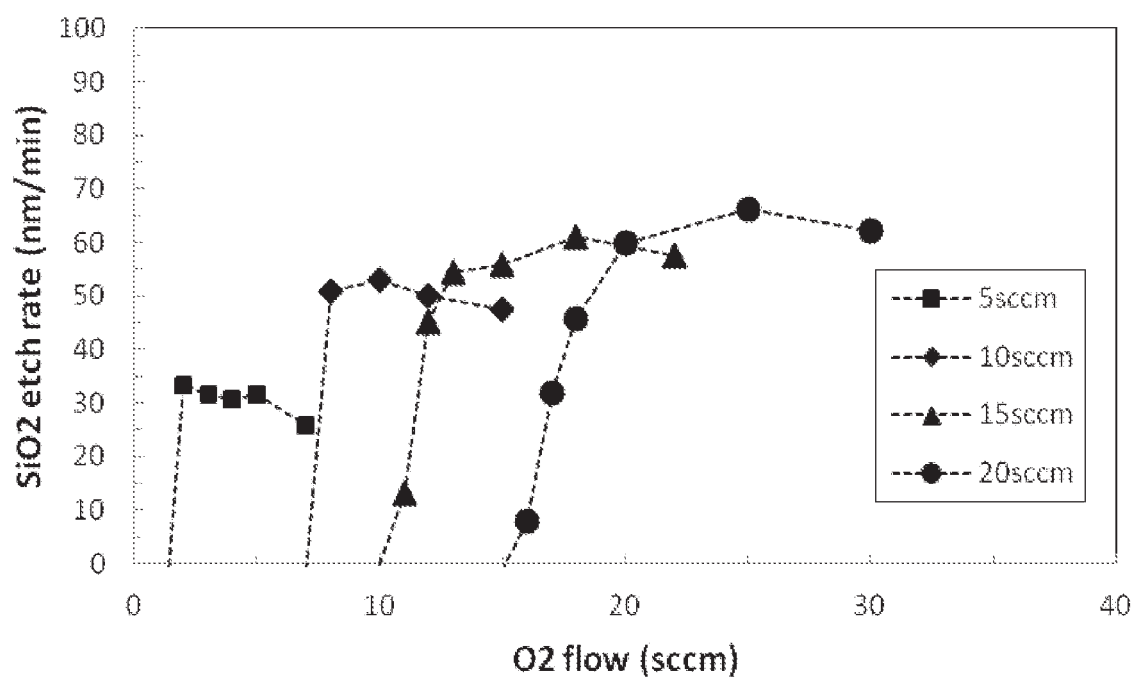
SiO₂ etch rate vs O₂ flow

FIG 15

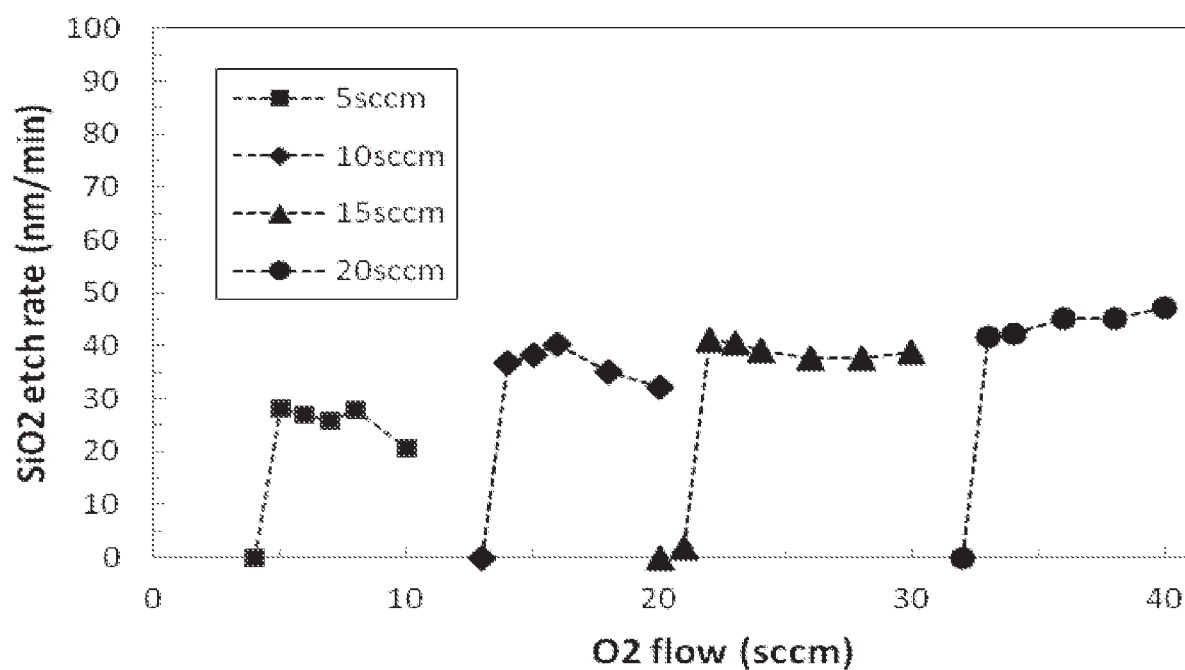
SiO₂ etch rate vs O₂ flow

FIG 16

9/11

Oxide selectivity vs O₂ flow

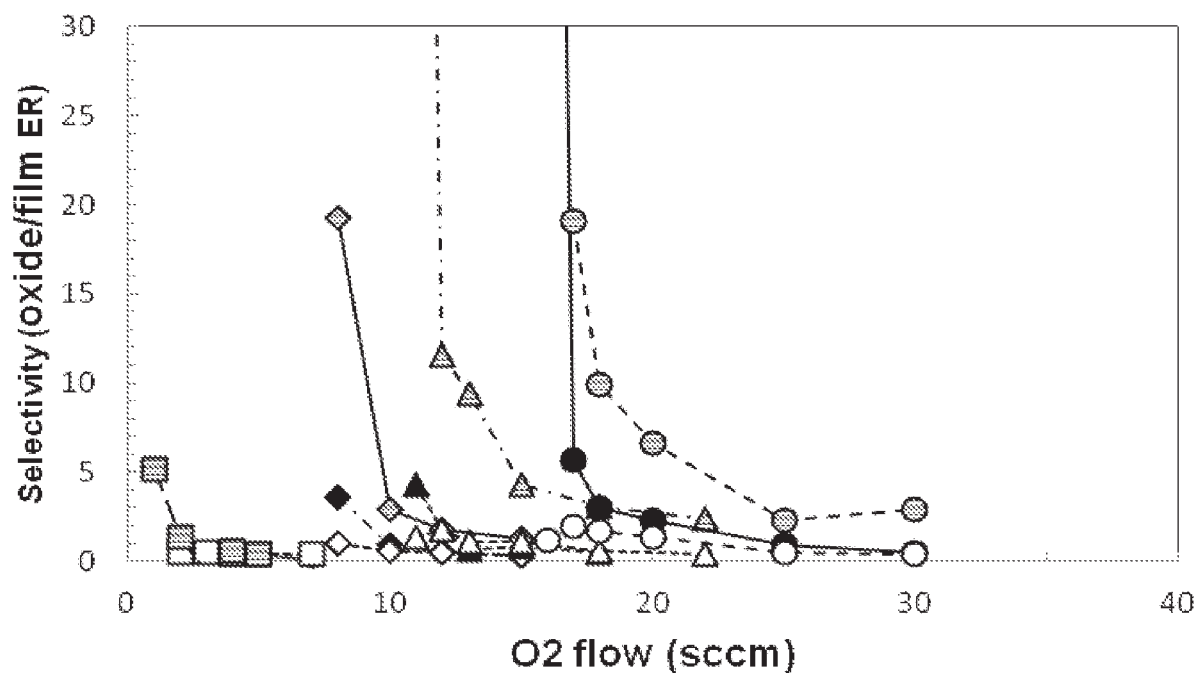


FIG 17

Oxide selectivity vs O₂ flow

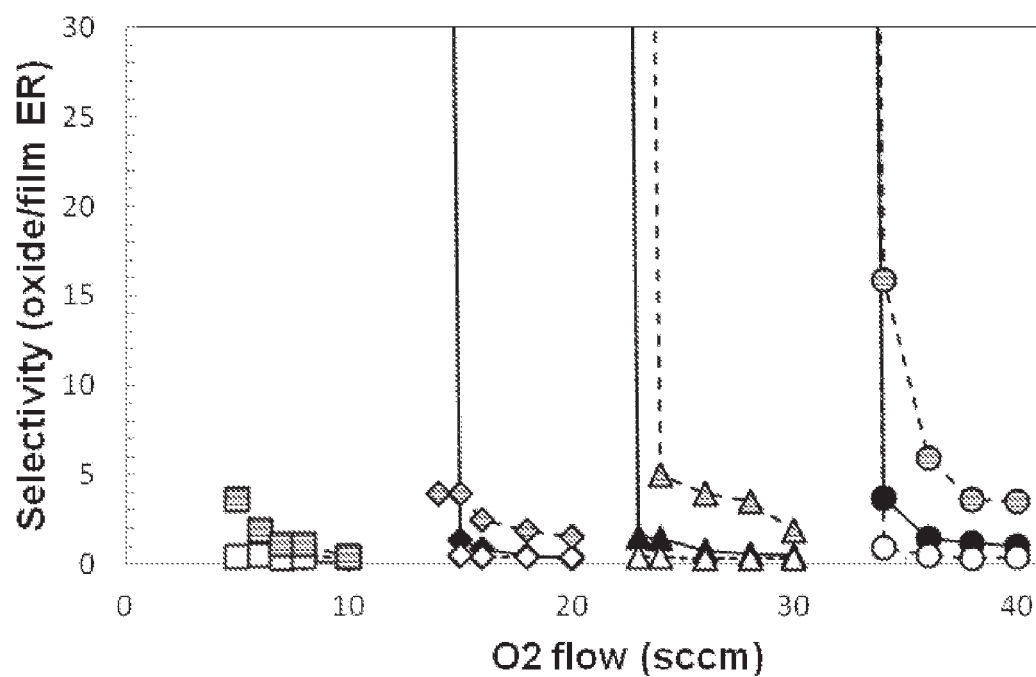


FIG 18

10/11

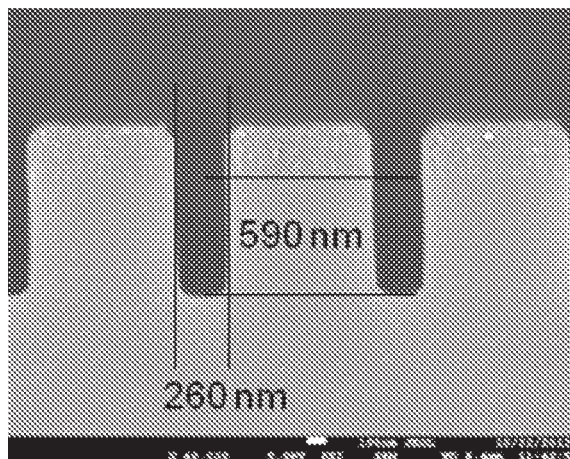


FIG 19

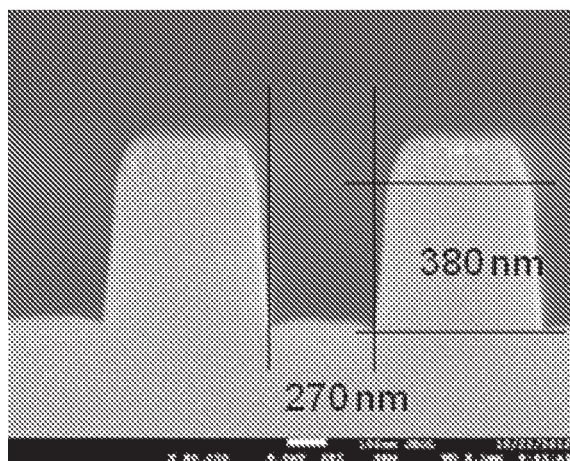


FIG 20

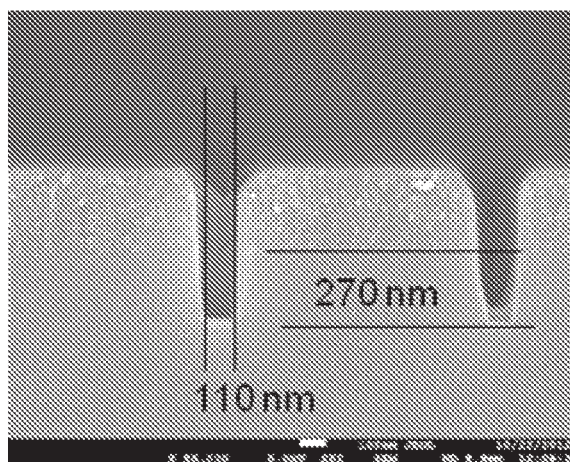


FIG 21

11/11

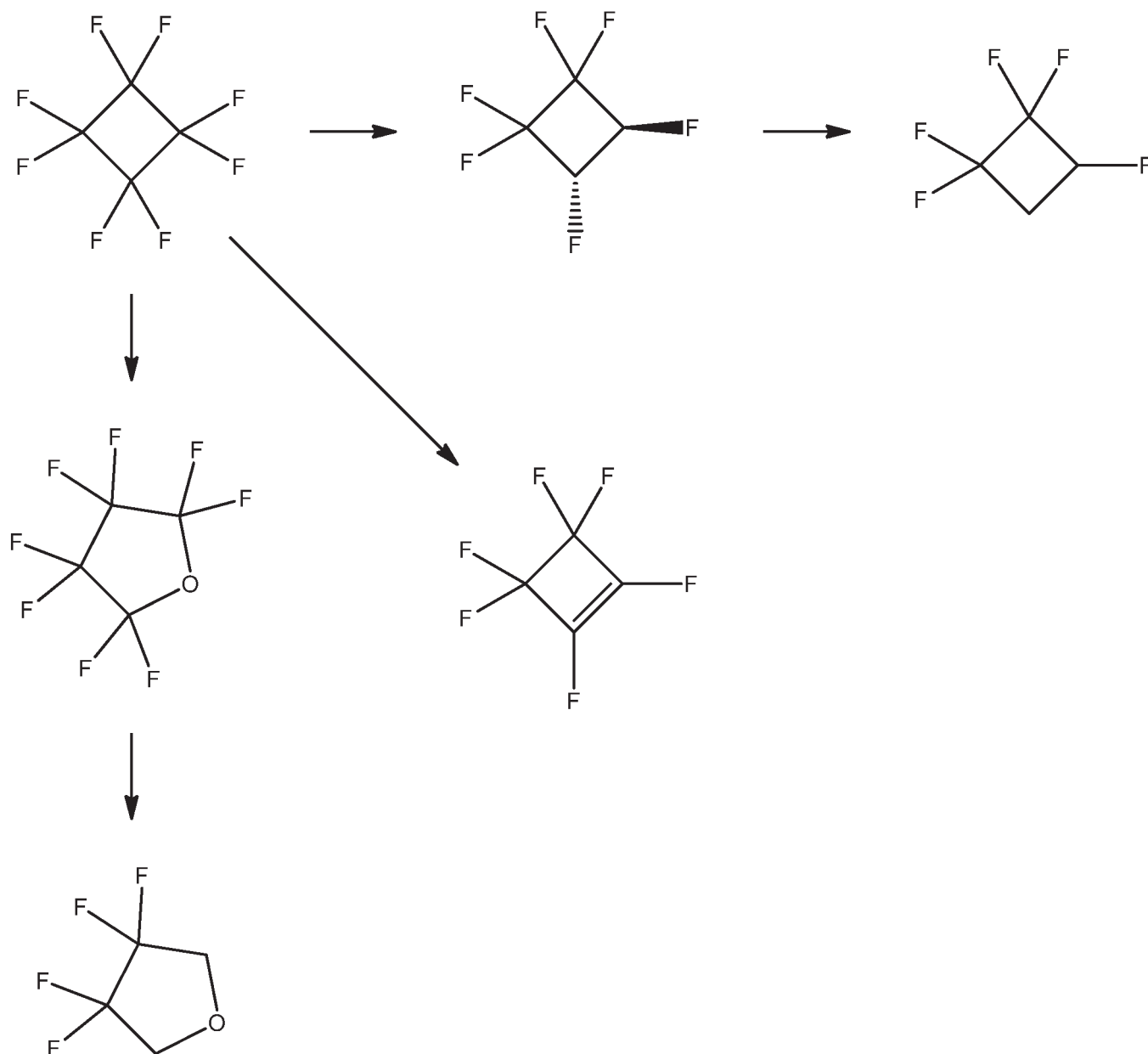


FIG 22